

SEC.584**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****In re PATENT APPLICATION of**

Ki-sang KIM et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: Lund, J.

Filed: January 26, 1999

**MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR AN
ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING****PRELIMINARY AMENDMENT****Honorable Assistant Commission of Patents and Trademarks,
Washington, D.C. 20231****Date: June 30, 2000**

Sir:

Preliminary to the examination of the above-identified application, please enter
the following amendments and remarks.

In the Specification:

Kindly amend the specification as follows:

Page 20, line 7, change "means" to --car--.

In the Claims:

Please amend the claims as follows:

1. (Amended) A multi-chamber system of an etching facility for manufacturing

semiconductor devices comprising:

